

ABSTRACT OF THE DISCLOSURE

The present invention provides a solid-state piezoelectric motion transducer device formed by thin films. The motion transducer is used for generating an electrical signal output proportional to motion quantities such as acceleration, vibration, and  
5 rotation. The motion transducer is also used for generating motion in response to applied electrical input signals. The precision thin-film piezoelectric elements are configured and arranged on a semi-rigid structure with a high degree of symmetry, thereby providing improved correlation between the electrical input or output signal quantities and the associated mechanical motion.